

IN THE CLAIMS

1. (currently amended) A method for analyzing defect information on a substrate, the method comprising the steps of:

inspecting the substrate to identify individual defect events, including at least one

of defects, defective pixels, and ~~defective defensive dice~~,

classifying the individual defect events into event patterns, ~~include~~-including at

least one of defect clusters and spatial signatures,

comparing the event patterns to a list of patterns of interest,

logically dividing the substrate into zones,

identifying the zones in which the patterns of interest exist on the substrate,

comparing the identified zones to a list of zones of interest,

identifying combinations of (1) patterns of interest on the substrate that (2) reside

within zones of interest on the substrate, and

comparing the identified combinations to a list of predetermined combinations

that are associated with defect causes, and

specifying at least one substrate defect cause based at least in part on matches

between the identified combinations and the predetermined combinations

and the associated defect causes.

2-20 (canceled)